

Amendments to the Claims

Claims 2, 12 – 17, 21, 40, 46 – 48, 51, and 52 without prejudice;

g listing of claims replaces all prior versions and listings of claims in

/ Amended) A substrate processing chamber comprising:

body;

p disposed on the chamber body; and

r-coupled plasma generator plate within the substrate processing

of transformer cores within the transformer-coupled plasma generator

ugh holes forming conduits from a first side of the transformer-

ate to a second side of the transformer-coupled plasma generator

passing through a first transformer core and a second of the conduits

former core.

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The substrate processing chamber of claim 1 wherein the plasma

/ Amended) The substrate processing chamber of claim 1 **further**

~~former core within the transformer-coupled plasma generating~~

y coil **being** is disposed to electro-magnetically couple to the first

nd primary coil **being** is disposed to electro-magnetically couple to

re within the transformer-coupled plasma generator plate, wherein

e second primary coil are connected to each other in series.

/ Amended) The substrate processing chamber of claim 1 wherein

e comprises ferrite material.

6. (Original) The substrate processing chamber of claim 1 wherein the transformer-coupled plasma generator plate includes a dielectric spacer between the first side and the second side, and a remainder of an outer surface of the generator plate comprises an electrical conductor.

7. (Original) The substrate processing chamber of claim 6 wherein the dielectric spacer is disposed within a conduit through the transformer-coupled generator plate.

8. (Original) The substrate processing chamber of claim 1 further comprising an alternating-current power supply configured to operate at a frequency of about 1 KHz-2 MHz.

A2  
9. (Original) A substrate processing chamber comprising:

a chamber body;

a chamber top disposed on the chamber body;

an alternating-current power supply; and

a transformer-coupled plasma generator plate having a plurality of through holes forming conduits from a first side of the transformer-coupled plasma generator plate within the substrate processing chamber to a second side of the transformer-coupled plasma generator plate within the substrate processing chamber, a first portion of the conduits passing through centers of a plurality of toroidal transformer cores within the generator plate and a second portion of the conduits not passing through centers of transformer cores, the generator having a first surface comprising metal, a second surface comprising metal, and a plurality of dielectric spacers disposed between the first surface and the second surface in each of the first portion of the conduits.

10. (Currently Amended) A plasma generator plate comprising:

a first side;

a second side;

a first conduit passing from the first side to the second side through a first transformer core within the plasma generator plate;

a second conduit passing from the first side to the second side through a second transformer core; and

a third conduit passing from the first side to the second side not passing through a transformer core.

11. (Original) The plasma generator plate of claim 10 further comprising a first dielectric spacer in a first secondary current path around the first transformer core.

12. – 17. (Canceled).

18. – 20. (Withdrawn).

21. (Canceled).

22. – 39. (Withdrawn).

40. (Canceled).

41. – 45. (Withdrawn).

46. – 48. (Canceled).

49. – 50. (Withdrawn).

51. – 52. (Canceled).